



## 7<sup>th</sup> Annual FIB SEM Workshop

**Thursday, February 27, 2014**

**Kossiakoff Center**

**Johns Hopkins Applied Physics Laboratory**

**Laurel, MD**

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*National Institute of Standards  
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**Thursday, February 27th, 2014**

8:00 AM Breakfast & Coffee

8:55 AM Welcome

Morning

9:00 AM **Nicholas Antoniou**

Harvard University

*Practical Considerations in Atom Probe Sample Making*

9:15 AM **Jeff Ditto**

CAMCOR/University of Oregon

*FIB-SEM Preparation of S/TEM Samples - Universal Methods for Application of the Wedge Technique and Suggestions for Optimization*

9:30 AM **Lucille Giannuzzi**

EXpressLO

*Specimen Preparation Flexibility with ex situ Lift Out*

9:45 AM **Lynne Gignac**, C. Breslin, J. Gonsalves, B. Harrison, K. Reuter

IBM T.J. Watson Research Center

*FIB Cross-section TEM Sample Preparation of Functionalized Nanopores in Thin Membranes*

10:00 AM **Jeff Marshman**, Soeren Eyhusen, Roland Salzer

Carl Zeiss Microscopy

*Ultra-Thin TEM Lamella Preparation on Challenging Specimens Using the "X2" Auto-tilting Sample Holder and Live BSE Thickness Monitoring*

10:15 AM *COFFEE BREAK*

10:45 AM **David MacMahon**

Micron Technology

*In-die STEM Method*

11:00 AM **Neal Magdefrau**, Julie Wittensellner

United Technologies Research Center

*FIB Applications for Industrial Research*

11:15 AM **Travis Rampton**

EDAX

*Grain Boundary Study of Sintered Nd-Fe-B Magnetic Materials*

11:30 AM **Sina Shahbazzmohamadi**, Navid Asadi Zanjani, Eric H. Jordan  
University of Connecticut  
*Quantitative Four Dimensional Non-destructive Imaging Using FIB and SEM: Application to Thin Film Coatings*

11:45 AM F. Bauer, **Scott Sitzman**, Cheryl Hartfield  
Oxford Instruments NanoAnalysis  
*Site-specific EDS/EBSD/TKD Analysis Performed on FIB Lift-out Samples*

12:00 PM **Michelle Husain**  
FEI Company  
*Image Processing & Advanced Characterization of 3D FIB-SEM Reconstructions with Avizo & Amira*

Lunch

12:15 PM Lunch

Poster Session

1:00 PM **Andrew J. Smith**, Andreas Rummel, Klaus Schock, Stephan Kleindiek  
Kleindiek Nanotechnik  
*Atom Probe Sample Preparation - A New Approach to Fabricating Ultra-sharp Atom Probe Samples*

**Daniel F. Lawrence**, David P. Olson, Hugues Francois Saint Cyr, David J. Larson  
Cameca

*FIB-SEM Sample Preparation for Atom Probe Tomography*

**Valery Ray**<sup>1</sup>, O. Zhao<sup>2</sup>, W.A. Chiou<sup>2</sup>, K. Zaitsev<sup>3</sup>, A. Zaitsev<sup>3</sup>

<sup>1</sup>Particle Beam Systems & Technology, <sup>2</sup>University of Maryland, <sup>3</sup>City University of New York

*Glancing Angle of Incidence Method for Bulk Material Removal in Cross-sectioning and TEM Sample Preparation by Ion Beam*

**Lynne M. Gignac**, Chris Breslin, C.-K. Hu

IBM T.J. Watson Research Center

*Use of EXpressLO™ Grids to Convert Ex-situ Liftout to In-Situ Liftout TEM Samples*

**Nabil Bassim**<sup>1</sup>, Joshua Caldwell<sup>1</sup>, Alexander Giles<sup>1</sup>, Leonidas Ocola<sup>2</sup>

<sup>1</sup>Naval Research Laboratory, <sup>2</sup>Argonne National Laboratory

*FIB Direct-Write Patterning of Metamaterial SiC Structures*

**Andrew Herzing**

National Institute of Standards and Technology

*Visualizing Phase Evolution in Organic Photovoltaic Material Systems via Cross-sectional FIB and Energy-Filtered Transmission Electron Microscopy*

Poster Session Continued

**Bradley T. De Gregorio**<sup>1,2</sup>, Rhonda M. Stroud<sup>2</sup>

<sup>1</sup>Nova Research, <sup>2</sup>Naval Research Laboratory

*Application of FIB for the Study of Shell Structure and Growth in the Barnacle Balanus Amphitrite*

Anahita Pakzad<sup>1</sup>, Stephen Mick<sup>1</sup>, **Danielle Elswick**<sup>1</sup>, Catherine Vartuli<sup>2</sup>, Jayhoon Chung<sup>3</sup>, Guoda Lian<sup>2</sup>

<sup>1</sup>Gatan Inc., <sup>2</sup>Kilby Imaging Lab/Texas Instruments, <sup>3</sup>ATD/Texas Instruments

*Application of Low Energy Broad Ion Beam Milling to Improve the Quality of FIB Prepared TEM Samples*

**Robert Keyse**

Lehigh University

*Gallium Isotope Effect Made Visible in FIB*

**Yaofang Zhang**, Jaafar A. El-Awady

Johns Hopkins University

*Micro-Mechanical Characterization of Ultra-High Strength Dendritic Tungsten Coatings for High Temperature Applications*

**Kedar Narayan**<sup>1</sup>, Cindy M. Danielson<sup>2</sup>, Ken Lagarec<sup>3</sup>, Bradley C. Lowekamp<sup>4</sup>, Phil Coffman<sup>1</sup>, Alexandre Laquerre<sup>3</sup>, Michael W. Phaneuf<sup>3</sup>, Thomas J. Hope<sup>2</sup>, Sriram Subramaniam

<sup>1</sup>National Cancer Institute/NIH, <sup>2</sup>Northwestern University, <sup>3</sup>Fibics, <sup>4</sup>National Library of Medicine/NIH

*Multi-resolution Correlative Focused Ion Beam Scanning Electron Microscopy: Applications to Cell Biology*

**Carl Justin Kamp**

Massachusetts Institute of Technology

*Application of the FIB/SEM/EDX System to the Field of Heterogeneous Catalysis for Automotive Aftertreatment Applications: An Up-and-coming Industry-wide Workhorse*

**Joseph Klingfus**<sup>1</sup>, Achim Nadzeyka<sup>2</sup>, Björn Wittmann<sup>2</sup>, Sven Bauerdick<sup>2</sup>, Brent Gila<sup>3</sup>

<sup>1</sup>Raith America, <sup>2</sup>Raith GmbH, <sup>3</sup>University of Florida

*Large-Area FIB Patterning by Continuously Moving Stage*

**Adam V. Steele**<sup>1</sup>, Brenton Knuffman<sup>1</sup>, Jabez J. McClelland<sup>2</sup>

<sup>1</sup>zeroK NanoTech, <sup>2</sup>CNST/National Institute of Standards and Technology

*Low Temperature Ion Source for Focused Ion Beam Applications*

Afternoon

2:30 PM **Brandon Van Leer**, Rick Passey

FEI Company

*Automated Large Area Image Acquisition for DualBeam FIB-SEM Characterization and Sample Preparation*

- 2:45 PM **Heayoung P. Yoon**<sup>1,2</sup>, Paul M. Haney<sup>1</sup>, Joshua Schumacher<sup>1</sup>, Kerry Siebein<sup>1</sup>, Yohan Yoon<sup>1,2</sup>, Nikolai B. Zhitnev<sup>1</sup>  
<sup>1</sup>CNST/National Institute of Standards and Technology, <sup>2</sup>University of Maryland  
*Effects of Focused-Ion-Beam Processing on Local Measurements of Semiconductor Solar Cells*
- 3:00 PM **Marco Sebastiani**<sup>1</sup>, E Bemporad<sup>1</sup>, C. Eberl<sup>2</sup>, A. Korsunsky<sup>3</sup>  
<sup>1</sup>University of Rome, <sup>2</sup>Fraunhofer IWM, <sup>3</sup>University of Oxford  
*Focused Ion Beam Techniques for Residual Stress Analysis at the Micron-scale*
- 3:15 PM Tony Moor<sup>1</sup>, **Matt Weschler**<sup>2</sup>  
<sup>1</sup>Datel Design and Development, <sup>2</sup>Technical Sales Solutions  
*Backside ROM Edit on 90nm CPU*
- 3:30 PM **Joel Fridmann**<sup>1</sup>, Brent Gila<sup>2</sup>, Paul Mazarov<sup>3</sup>, Achim Nadzeyka<sup>3</sup>, Sven Bauerdick<sup>3</sup>  
<sup>1</sup>Raith America, <sup>2</sup>University of Florida, <sup>3</sup>Raith GmbH  
*Non-Gallium FIB Alternatives for Nanofabrication*
- 3:45 PM *COFFEE BREAK*
- 4:15 PM **Toshiaki Fujii**, Jamil J. Clarke, Mike Hernandez  
 Hitachi High Technologies  
*Redefining the FIB: Advancing Sequential Segmentation to the Next Level*
- 4:30 PM **Hamed Parvaneh**, Robert Hull  
 Rensselaer Polytechnic Institute  
*Chemical Analysis Using Focused Ion Beam-Induced Auger Electron Spectroscopy*
- 4:45 PM F.A. Stevie<sup>1</sup>, L. Sedlacek<sup>2</sup>, P. Babor<sup>3</sup>, J. Jiruse<sup>2</sup>, **E. Principe**<sup>4</sup>, K. Klosova<sup>2</sup>  
<sup>1</sup>North Carolina State University, <sup>2</sup>TESCAN, <sup>3</sup>Central European Institute of Technology, <sup>4</sup>TESCAN-USA  
*Quantitative TOF-SIMS on a FERA Platform Using Ar and Xe Plasma Sources*
- 5:00 PM **Kevin A. Twedt**<sup>1,2</sup>, Thomas Lam<sup>1</sup>, Lei Chen<sup>1</sup>, Jabez J. McClelland<sup>1</sup>  
<sup>1</sup>CNST/National Institute of Standards and Technology, <sup>2</sup>University of Maryland  
*Scanning Ion Microscopy with Low Energy Lithium Ions*
- 5:15 PM **Huimeng Wu**<sup>1</sup>, David Ferranti<sup>1</sup>, Lewis Stern<sup>1</sup>, John Treadgold<sup>1</sup>, Chuong Huynh<sup>1</sup>, Joseph Myers<sup>2</sup>, Erik McCullen<sup>2</sup>  
<sup>1</sup>Carl Zeiss Microscopy, <sup>2</sup>IBM Essex Junction  
*Nanofabrication with a Neon Ion Beam*
- 5:30 PM Wrap-up
- 5:30 PM **Happy Hour at the Kossiakoff Center, APL**